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1 Exposure tool effects on OPC

Detje, M.; Hassmann, J.; Kurth, K.

Microprocesses and Nanotechnology Conference, 2002. Digest of Papers.

Microprocesses and Nanotechnology 2002. 2002 International, 6-8 Nov. 2002

Pages:298

[Abstract] [\[PDF Full-Text \(157 KB\)\]](#) IEEE CNF

2 Subwavelength lithography (PSM, OPC)

Terasawa, T.

Design Automation Conference, 2000. Proceedings of the ASP-DAC 2000. Asia and South Pacific, 25-28 Jan. 2000

Pages:295 - 300

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3 The double exposure strategy using OPC and simulation and the performance on wafer with sub-0.10 µm design rule in ArF lithography

Se-Young Oh; Wan-Ho Kim; Hyoung-Soo Yune; Hee-Bom Kim; Seo-Min Kim;

Chang-Nam Ahn; Young-Mog Ham; Ki-Soo Shin;

Microprocesses and Nanotechnology Conference, 2001 International, 31 Oct.-2

Nov. 2001

Pages:12 - 13

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4 Study on the optimization of high transmittance attenuated phase-shifting mask by design f experiment

Wen-an Leong; Hsien-yun Lin; Wen-long Yeh;

Microprocesses and Nanotechnology Conference, 2002. Digest of Papers.

Microprocesses and Nanotechnology 2002. 2002 International, 6-8 Nov. 2002

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[Abstract] [\[PDF Full-Text \(184 KB\)\]](#) IEEE CNF

5 Low energy e-beam proximity lithography (LEEPL)

Utsumi, T.;

Microprocesses and Nanotechnology Conference, 1999. Digest of Papers.

Microprocesses and Nanotechnology '99. 1999 International , 6-8 July 1999

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